



Attorney Docket No. 740756-2681

*Handwritten signature: J. H. Chong*

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of: )  
Akiharu MIYANAGA et al. ) Group Art Unit: 1762  
Serial No. 10/728,987 )  
Filed: December 8, 2003 ) Examiner: W. Markham  
For: PULSED PLASMA CVD METHOD )  
FOR FORMING A FILM ) Confirmation No.: 1100  
(as amended) )

**SUBMISSION OF A LISTING OF REFERENCES CITED IN PARENT  
APPLICATIONS, PURSUANT TO MPEP 609(I)(A)(2)**

U.S. Patent & Trademark Office  
2011 South Clark Place  
Customer Window, Mail Stop Amendment  
Crystal Plaza Two, Lobby, Room 1B03  
Arlington, VA 22202

Sir:

The Applicants submit a listing of each of the references cited in parent Application No. 09/636,222, as well predecessor Application Nos. 09/262,853; 08/740,140; 08/463,058; 08/426,483; 08/120,222 and 07/763,595. The MPEP Chapter 609 @ (I)(A)(2) sets forth that each of the references from the predecessor applications must be considered by the Examiner, and, further, sets forth that if those references are to be printed on any issued patent from the above identified application, then a "listing" of those references must be provided by the Applicants. Please find attached a listing of each of the references cited in each of the parent (predecessor) applications.

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